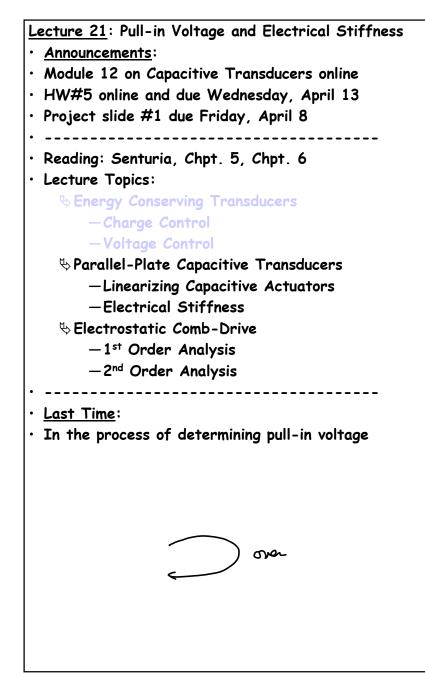
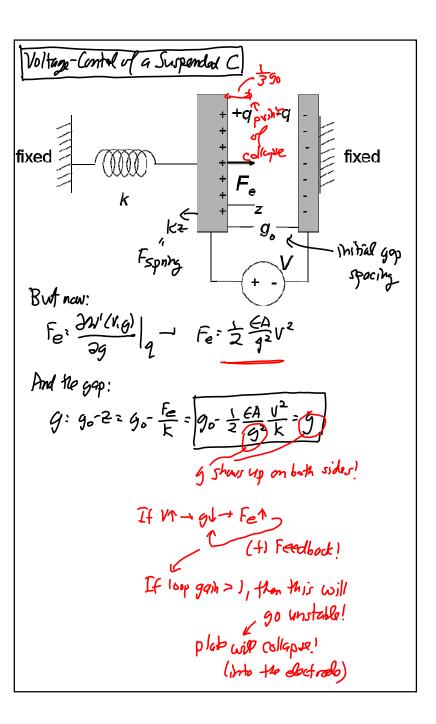
<u>EE C247B/ME C218</u>: Introduction to MEMS Design <u>Lecture 21w</u>: Pull-in Voltage and Electrical Stiffness



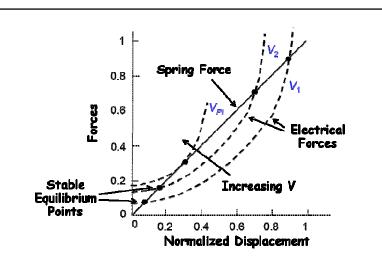


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Charge: (for a stake gap) $2: \frac{\mathcal{W}(V,g)}{\partial V} = CV \vee (as expected)$ Stability Analysis => defermine under what conditions voltese control will cause collapse of the plates: First : $Fe-Fspinhg = \frac{EAV^2}{2g^2} - \frac{k(g_0-g)}{spinhg}$ What happens when I change q by q small increment dg? got an increment in the net atreative force Fist $\frac{dF_{ref}}{(-)} = \frac{\partial F_{ref}}{\partial g} dg = \left[-\frac{\epsilon A v^2}{g^3} + k\right] dg$ $\frac{f_{ref}}{(-)} = \frac{\partial F_{ref}}{\partial g} dg = \left[-\frac{\epsilon A v^2}{g^3} + k\right] dg$ $\frac{f_{ref}}{(-)} = \frac{f_{ref}}{(-)} + \frac{f_{ref}$ need Frett - Offret= (-) This mothe (+)! -+ otherwise, the plades collegue! Thur: $\left[K > \frac{\epsilon A V^2}{R^3} \right]$ (for a stable uncollagued System)

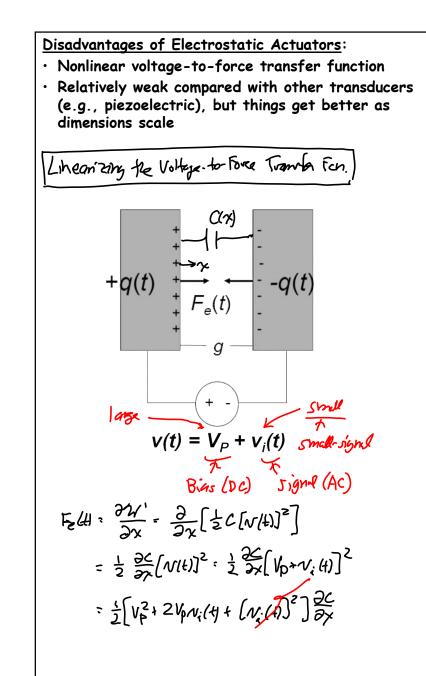
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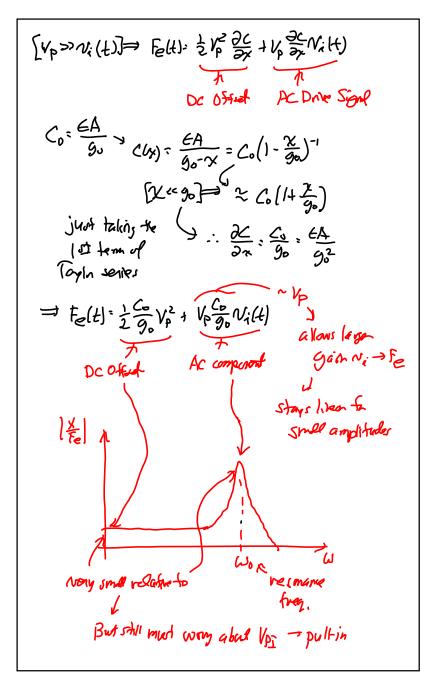
Advantages of Electrostatic Actuators:

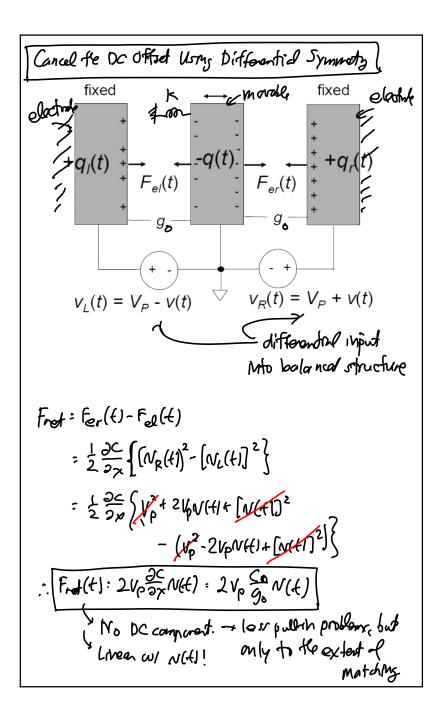
- Easy to manufacture in micromachining processes, since conductors and air gaps are all that's needed → low cost!
- \cdot Energy conserving \rightarrow only parasitic energy loss through I²R losses in conductors and interconnects
- Variety of geometries available that allow tailoring of the relationships between voltage, force, and displacement
- Electrostatic forces can become very large when dimensions shrink \rightarrow electrostatics scales well!
- Same capacitive structures can be used for both drive and sense of velocity or displacement
- Simplicity of transducer greatly reduces mechanical energy losses, allowing the highest Q's for resonant structures



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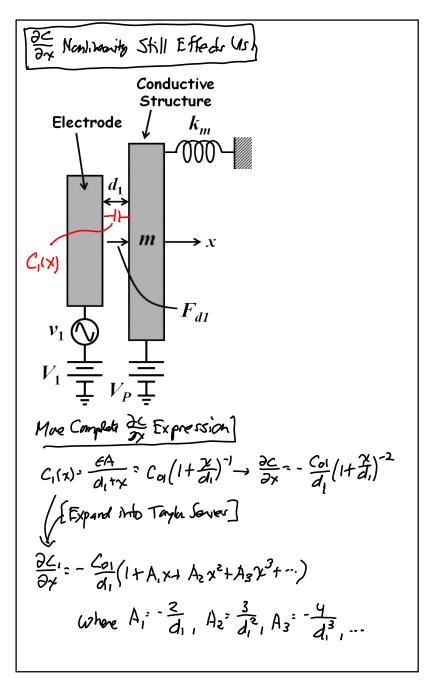
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 $F_{II} = \frac{1}{2} \frac{\partial C_{I}}{\partial x} (V_{p} - V_{I} - N_{i})^{2} = \frac{1}{2} \frac{\partial C_{I}}{\partial x} (V_{pI} - N_{i})^{2}$ Vp1 Vp-V, N,12(1+cosdust [Small displacements: x « di] N,2 [N,12cus2wst $F_{al} = \frac{1}{2} \left(-\frac{C_{ol}}{A_{i}} \right) (1 + A_{i} z) (v_{pl}^{2} - 2v_{pl} v_{i} + v_{i}^{2}) (v_{pl} + v_{i}^$ $= \frac{1}{2} \left(-\frac{C_{01}}{a_{1}} \right) \left\{ V_{P1}^{2} - 2V_{P1}N_{1} + N_{1}^{2} + A_{1}V_{P1}^{2} \right\}$ - JANAXU, + AIKU, " Reimana: 201 cg (X) Small X 2000 @ vesmare: $\chi = \frac{QF_{al}}{ik} = \frac{Q}{ik} \frac{\partial C}{\partial x} V_{Pl} v_{l}$ 90° phase shift N= Wilcoswot ~ x= 1x15hwot 90° phase-shift

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